



SEMICONDUCTOR



ANALYTICAL
INSTRUMENTS



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CHEMICAL
INDUSTRY



THE VACUUM PARTICLE TRAP

To protect your vacuum pumps
in harsh duties for a long lifetime



The Vacuum Particle Trap has been engineered by Ebara engineers in Dresden, Germany. Fixed between the process chamber and the pump inlet, the vacuum particle trap protects the pump against contamination with particles.

BENEFITS

- Extends the vacuum pump's life cycle
- Filter particles in harsh duties
- Different sizes of particle containers available
- Retrofittable at any time
- Autoclean option
- Engineered and produced in Germany



Length	850 to 920 mm
Weight	22 kg
Diameter	220 mm
Autoclean	on demand
Material	Stainless steel



All data without guarantee.

For further information, technical data or drawings please contact: marketing@ebara-pm.eu

EBARA is a worldwide leading global manufacturer of vacuum and semiconductor systems used in the production of wafers, liquid crystals, solar cells and other products requiring advanced

EBARA Precision Machinery Europe (EPME) is part of the Japanese EBARA Group and employs approximately 230 people in Europe. The portfolio includes dry and turbo molecular vacuum pumps as well as gas abatement systems. In addition, EPME sells state-of-the-art CMP tools, wafer bevel polishing and substrate coating systems. In Europe, EPME has a central warehouse and two overhaul centres for vacuum pumps.

EBARA supports



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